

**Notice of References Cited**

Application/Control No.

10/085,421

Applicant(s)/Patent Under  
Reexamination  
MCDONALD ET AL.

Examiner

Michael Cygan

Art Unit

2855

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**NON-PATENT DOCUMENTS**

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	V	MKS Instruments Brochure, "Pressure-Based Mass-Flo® Controller for Ion Implant Applications", June 2001.
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\*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)  
Dates in MM-YYYY format are publication dates. Classifications may be US or foreign.